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Abstract

A method for qualifying and/or manufacturing an optical surface includes:

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arranging a first substrate having a first surface and a second surface opposite the first surface in a beam path of a first incident beam with the first surface facing towards the first incident beam, and taking an interferometric measurement of the second surface;

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arranging the first substrate in the beam path of the first incident beam with the second surface facing towards the first incident beam, and taking an interferometric measurement of the second surface;

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arranging a third surface of a second substrate in a beam path of a second incident beam, and taking an interferometric measurement of the third surface;

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arranging the third surface of the second substrate and the first substrate in the beam path of the second incident beam, and taking an interferometric measurement of the third surface.

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